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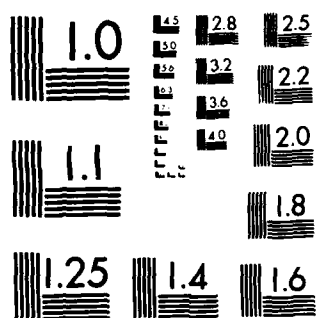
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SEATTLE DEPT OF MATERIALS SCIENCE AND ENGINEER
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This report describes the status of a transmission electron microscopy system that was purchased through a grant (AFOSR-87-0078) entitled "Request for a High Voltage/High Resolution Scanning Transmission Electron Microscope." The microscope purchased is a Philips EM 430T; accessories bought with the microscope are an energy-dispersive x-ray spectrometer (EDS) and an electron energy loss spectrometer (EELS). The tests at all modes of analysis have been completed and the results indicate that the instrument and its peripherals operate at their expected performance.

The system has already proven to be an indispensable tool in our DoD-supported projects on the development of advanced materials and it is expected that it will serve as a primary characterization tool in future projects.

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FINAL REPORT

on the

**ACQUISITION OF A HIGH VOLTAGE/HIGH
RESOLUTION TRANSMISSION ELECTRON
MICROSCOPE**

submitted to

AIR FORCE OFFICE OF SCIENTIFIC RESEARCH

by

I. A. Aksay and M. Sarikaya

*Department of Materials Science and Engineering
University of Washington FB-10
Seattle, Washington 98195*

August 1988

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1.0 SUMMARY

This report describes the status of a transmission electron microscopy system that was purchased through a grant (AFOSR-87-0078) entitled "Request for a High Voltage/High Resolution Scanning Transmission Electron Microscope." The microscope purchased is a Philips EM 430T; accessories bought with the microscope are an energy-dispersive x-ray spectrometer (EDS) and an electron energy loss spectrometer (EELS). The tests at all modes of analysis have been completed and the results indicate that the instrument and its peripherals operate at their expected performance.

The system has already proven to be an indispensable tool in our DoD-supported projects on the development of advanced materials and it is expected that it will serve as a primary characterization tool in future projects.</

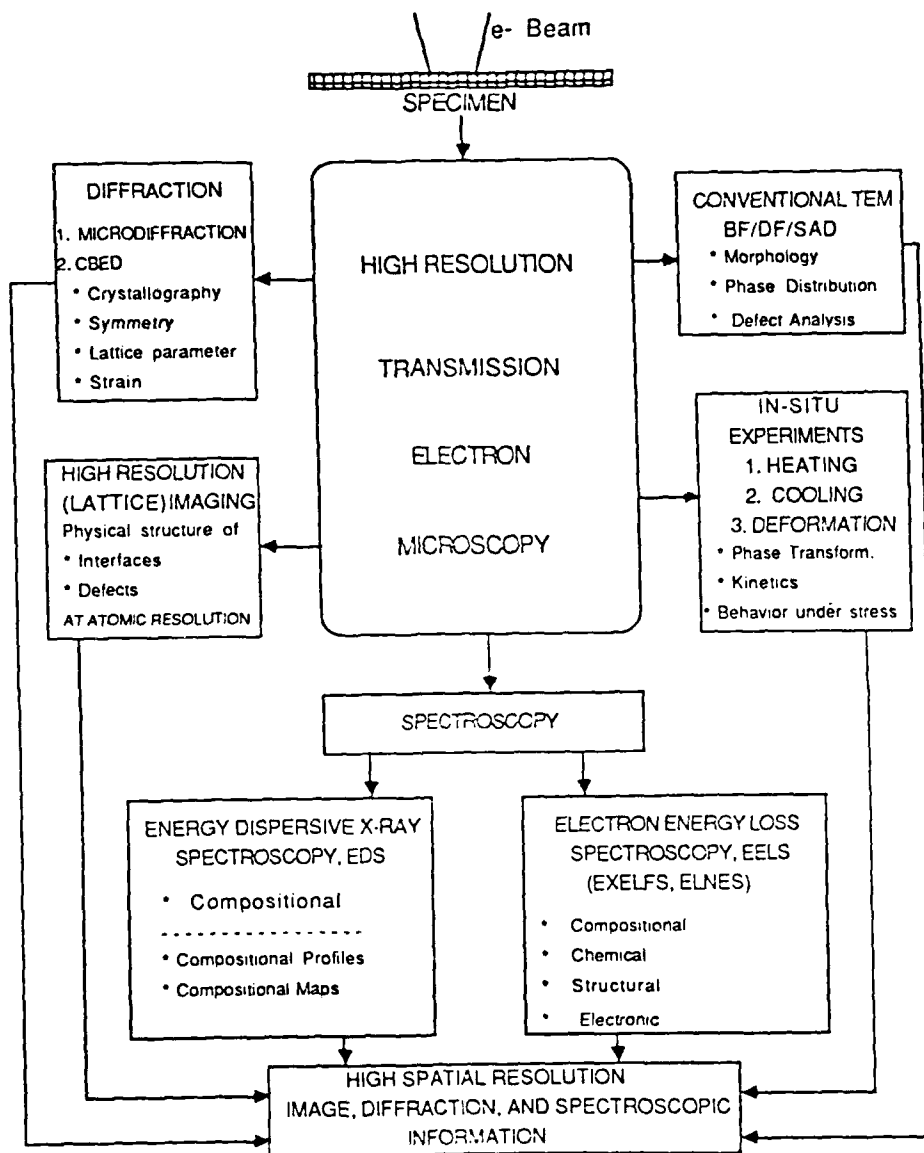


Figure 1: Schematic illustration of TEM techniques

The Philips EM 430T has the following features:

- A maximum operational voltage of 300 kV.
- Peripheral devices consisting of a scanning transmission electron microscopy unit, an energy dispersive x-ray spectrometer, and an electron energy loss spectrometer.
- Small probe-forming capabilities.
- Special specimen holders used for various analytical purposes.

The short descriptions of the system and its attachments are given below.

2.1 The Transmission Electron Microscope, TEM

The transmission electron microscope is a Philips EM 430T model TEM/STEM instrument which can be used for high resolution imaging and the formation of small electron probe, used in diffraction and spectroscopic applications. It displays images formed by the transmitted electrons on a phosphorous screen. The operating voltage can be varied from 0 to 300 kV at 1 eV steps with an external controller. Maximum magnifications on the photographic plate are $750,000\times$, $650,000\times$, and $550,000\times$ at voltages of 100, 200, and 300 kV, respectively. The smallest probe size that can be formed in the TEM mode is about $40\text{ \AA}$, and image resolution is $2.0\text{ \AA}$ as confirmed by HREM (see Section 3.1).

The TEM and all the attachments (except EELS) were purchased from the North American Philips Co., Philips Electronic Instruments, 1381 McCarthy Boulevard, Milpitas, CA 95035; contact person: Mr. W. R. Turnquist, (408) 263-7000.

2.2 Scanning Transmission Electron Microscopy Unit, STEM

This unit has a separate detection system for scanned and transmitted electrons and operates at all comparable voltages of the TEM. In the image mode, the maximum image

magnification is $400,000\times$, and the image is displayed on a cathode ray tube (CRT). In the diffraction mode, the minimum probe size is $20\text{ \AA}$. The STEM unit has independent focussing and astigmatism correction features. Its main use is the formation of small electron probes, principally for compositional analysis using EDS.

2.3 Energy Dispersive X-Ray Spectrometer, EDS

This unit includes a Si(Li) solid state detector horizontally mounted to the microscope column at the sample level and it is mainly used for quantitative elemental analysis. It has a thin beryllium window and windowless options; both features are used for the detection of characteristic x-rays that are produced during interaction

2.5 Specimen Holders

There are four specimen holders and each is used for a specific purpose. These are described below.

2.5.1 Single Tilt Holder

With this holder, the sample can only be tilted in one direction, but the holder has high mechanical stability. Also, sample loading is straightforward. It is mainly used for high resolution imaging of small suspended particles on an amorphous TEM grid (e.g., on a carbon film).

2.5.2 Double Tilt Holder

Tilting can be performed in two orthogonal directions by $\pm 30^\circ$ and $\pm 45^\circ$. Its main use is conventional microscopy and crystallography studies (through high-angle diffraction).

2.5.3 Tilt-Rotation Holder

Both tilting ($\pm 45^\circ$) and rotation (between 0° and 360°) can be performed with this holder. Its main usage is in crystallographic analysis.

2.5.4 Low Temperature-Low Background Holder

This holder can be cooled to -175°C by liquid nitrogen, which reduces thermal vibration in the sample. It also has a low x-ray background feature and is, therefore, heavily used in EDS analysis. For beam-sensitive materials, such as superconducting ceramics or bioparticles, this holder can be used for diffraction, EDS, and EELS studies since it reduces the radiation damage to the sample.

3.0 Performance Tests

The microscope can be operated at four analysis modes of advanced transmission electron microscopy. These are: high resolution imaging, converging beam electron diffraction, energy dispersive x-ray spectroscopy, and electron energy loss spectroscopy. This section describes the tests that have been undertaken in each of these modes to establish the performance of the microscope at respective operation modes.

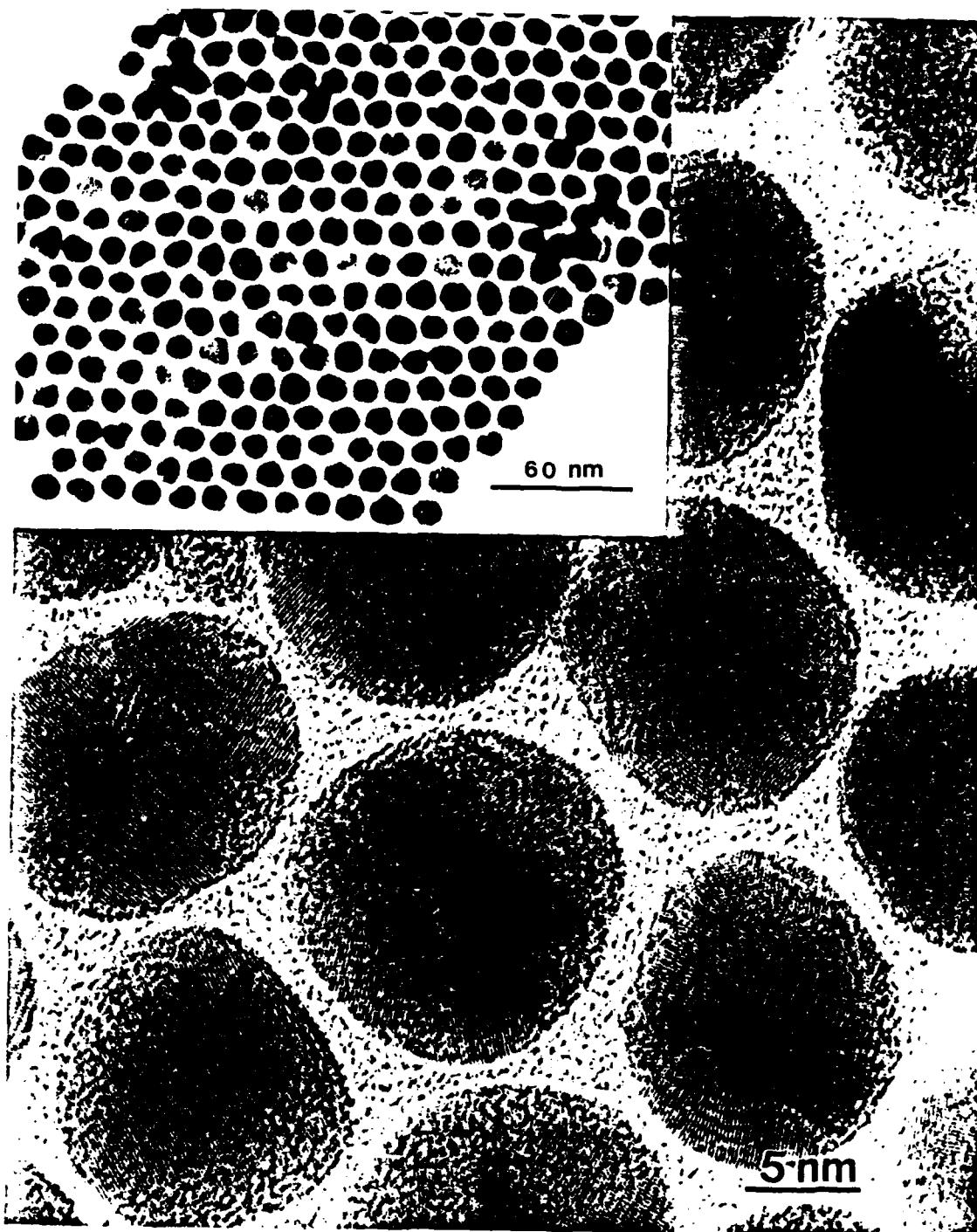
3.1 High Resolution Electron Microscopy

HREM imaging is a technique in which thin samples with periodic arrangements of atoms (crystals) are imaged in a projection in the direction of the electron beam. Therefore, it is an atomic resolution imaging revealing the atomic packing of matrix and its defect structures, structures of boundaries, interfaces, and small particles. The instrumental resolution of the microscope, d_r , is dictated mainly by the optical defect in the objective lens (i.e., by C_s , which is the spherical aberration coefficient of the objective lens) and by the kinetic energy of the incoming electrons (i.e., by the acceleration voltage, or by the wavelength, λ , of electrons) through the Shertzer formula,¹

$$d_r = 0.7 C_s^{1/4} \lambda^{3/4}$$

The value for C_s for the Philips EM 430T is 2.0 mm and at 300 kV accelerating voltage ($\lambda = 0.0197\text{\AA}$), the theoretical resolution becomes 2.3 $\text{\AA}$.

The resolution tests have been performed by imaging colloiddally prepared gold particles suspended on a thin (50 $\text{\AA}$) and amorphous carbon film. Figure 2 is an image from such a sample. It reveals the atomic arrangements in several gold particles projected in various orientations. As can be seen in particle A, both 111 ($d_{111} = 2.35\text{\AA}$), and 200 ($d_{200} = 2.04\text{\AA}$) fringes are resolved (the image was taken at a defocus value lower than the Shertzer value producing a reverse contrast, i.e., atoms appear "bright" in the image).



3.2 Convergent Beam Electron Diffraction, CBED, and Microdiffraction

Because of the twin lens arrangement of the objective lens, i.e., the upper and lower pole pieces of the objective lens about the sample, small electron probes can be formed. This is done mainly by the excitation of the upper pole piece of the objective lens. The theoretical probe sizes that can be formed under different condensor-1 (C1) excitations and condensor aperture (CA) sizes in the TEM and STEM modes are listed in Table I.

Selector position	LM range (<
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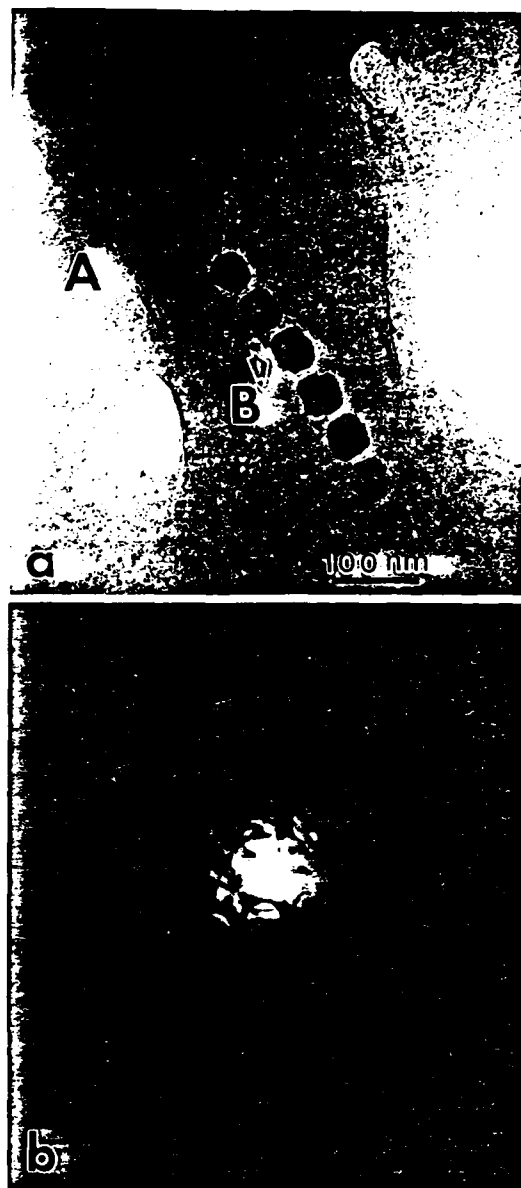
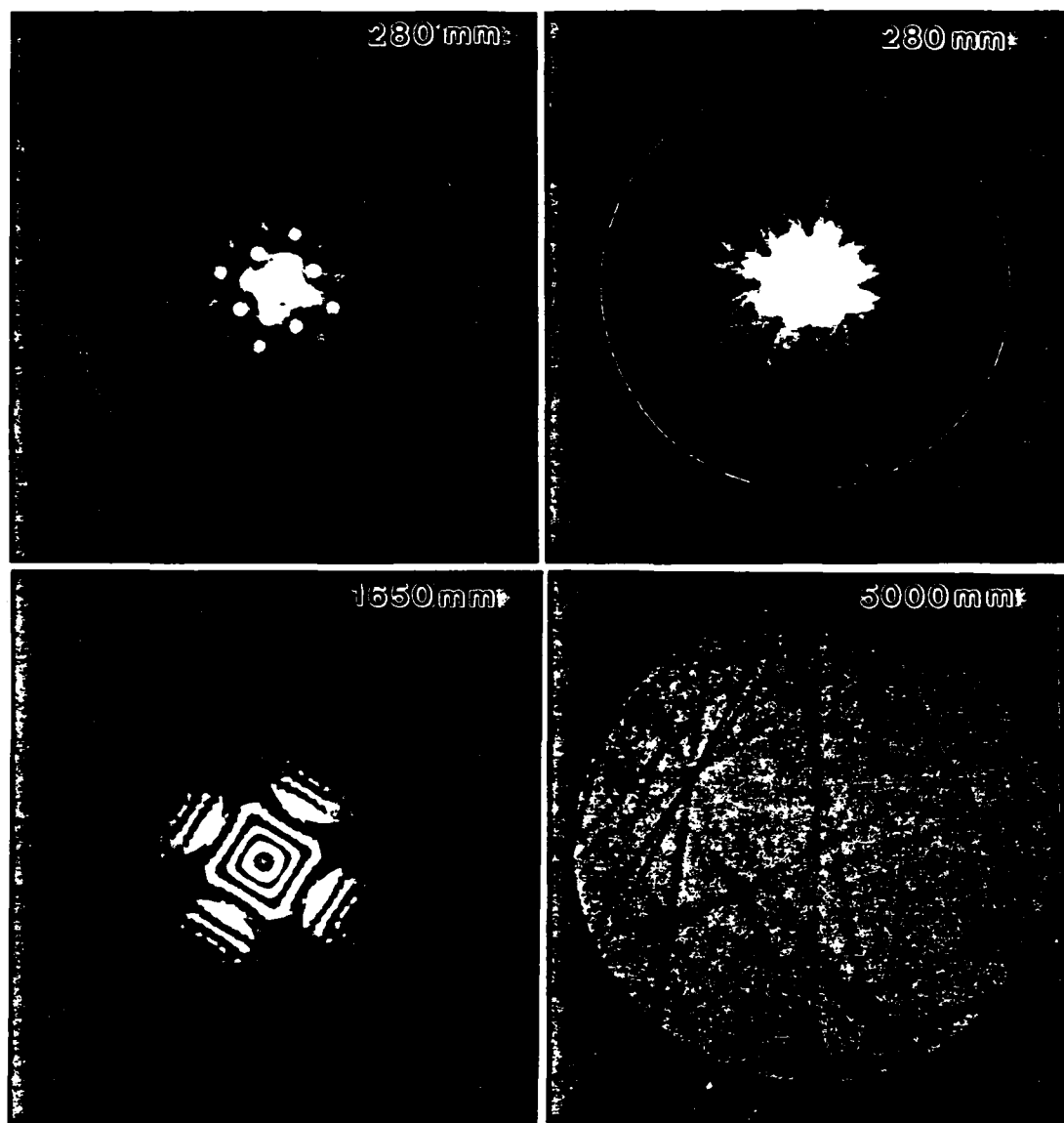


Figure 3. Bright field (a) and microdiffraction pattern (b) taken



Convergent beam experiments were done by using single crystal Si (dc, $a = 5.4309 \text{ \AA}$). The experiments were performed to check the stability of the electron probe during the recording of the CBED patterns and to reveal high order Laue zone (HOLZ) lines located in the forward scattered beam. In order to decrease the thermal vibrations and increase the sharpness of the diffraction lines, experiments were done by using the low temperature holder (specimen temperature equalled was -170°C). Figure 4 exhibits CBED patterns at various camera lengths to reveal symmetry and diffraction features in the whole pattern, in the zero layer, and in the bright field disc.³ The revelation of HOLZ lines in the BF disc by $[100]$ orientation, which have low scattering amplitudes, is especially interesting and can only be done by using the low temperature holder.

shown in Figure 5a as a reference. The spectrum shown in Figure 5b. is from an intergranular phase which was identified as cuprous oxide (Cu_2O) (see Appendix).

LABEL = 1-2-3							
A. 362.630 LIVE SECONDS				B. 74.469 LIVE			

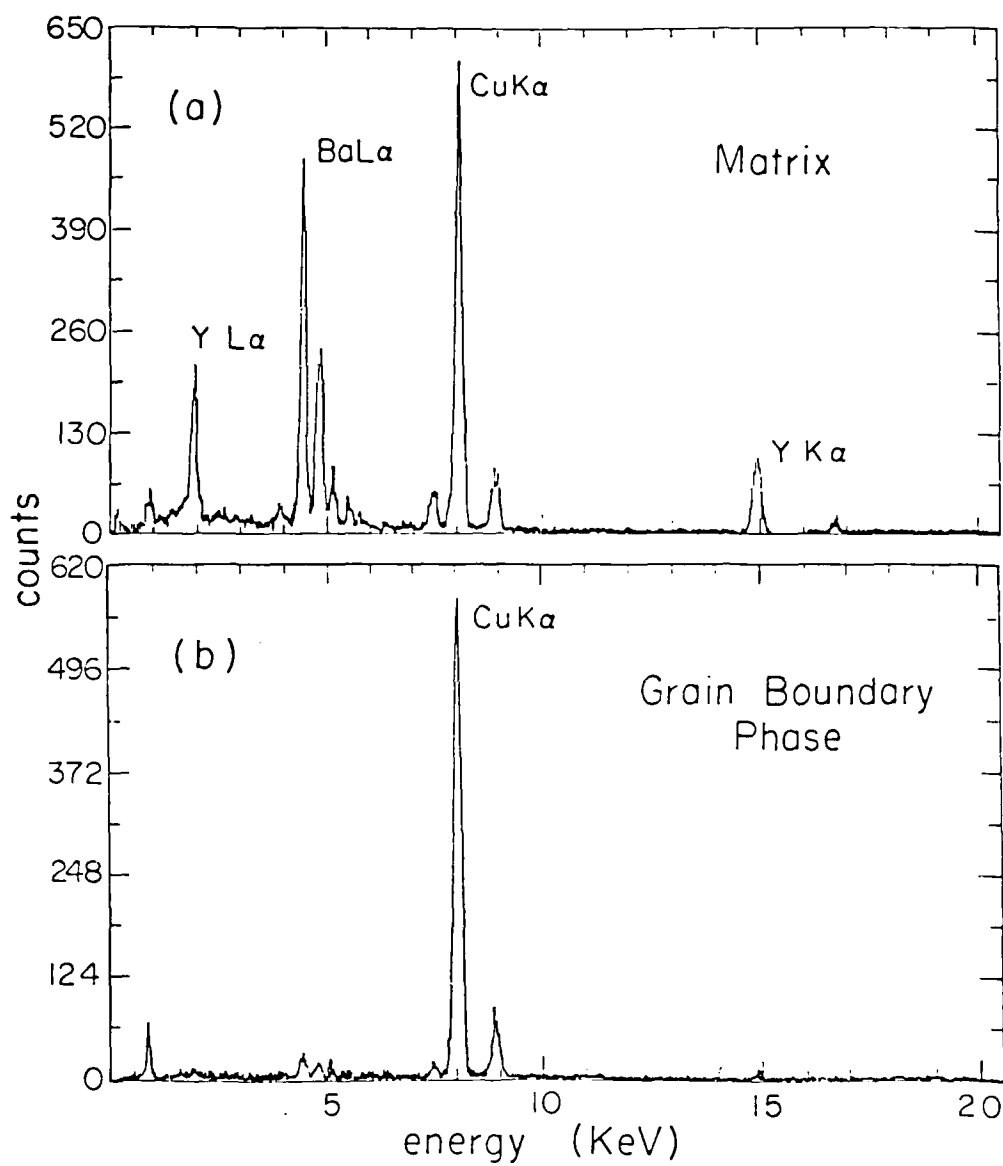


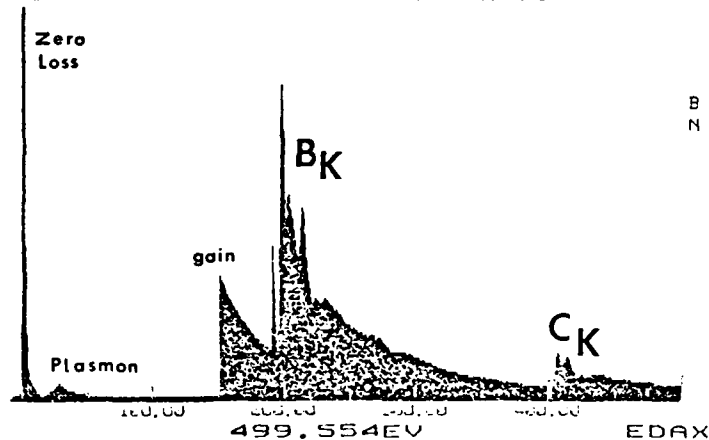
Figure 5. EDS spectra of 1:2:3 phase (a) and of intergranular phase (b). Note that in (b), there are only peaks corresponding to Cu. The intergranular phase has been identified to be cuprous oxide (Cu_2O) (see Appendix for the *J. Amer. Soc.* paper on this subject).

3.4 Electron Energy Loss Spectroscopy (EELS)

The EELS is the study of energy distribution of electrons which have interacted with a specimen.^{5,6} The number of electrons which have lost a certain amount of energy from their primary value (the ordinate) is plotted with respect to their respective energy loss, ΔE (abscissa) in an energy loss spectrum (Figure 6a). The EEL spectrum, in this respect, resembles an x-ray absorption spectrum with edges corresponding to absorption edges.⁶ Both the intensity under each edge (after background subtraction and multiple scattering effects are excluded), as well as the detailed shape and the energy threshold of each edge, are used for compositional and atomic binding information.

EELS technique is particularly useful for the detection and quantification of low atomic number

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 LBL: Boron Nitride High Res.
 FS: 29979 MEM: A CNT: 851



4.0 Research Projects

4.1 Current DoD Supported Research

4.1.1 Microdesigning of Lightweight/High Strength Ceramic Materials

I.A. Aksay

Sponsor: AFOSR/DARPA; Program Manager: D. R. Ulrich

understanding of the important parameters involved in the dispersion, consolidation, and sintering of particles in the size range of 10^{-9} to 10^{-3} m. These particles may be spheroidal, platelike, or rodlike, and may form a highly dispersed or agglomerated suspension. Surfactants or polymers may be added to a suspension to improve the consolidation step, resulting in the tailored packing of the particles in the green microstructure. Densification may take place with the addition of heat and/or pressure. This program studies each of these areas in detail in order to improve upon current processing methodology in designing and producing desired microstructural features.

In the high density consolidation of nanosized particles with surfactants (synthetic or biopolymers, refer to Section 4.1.2), control of the evolution of the structures is of great importance. Therefore, direct observation of the cluster structures is necessary. Structures of clusters or aggregates of small particles can be studied directly by transmission electron microscopy techniques (Fig. 7).<



Fig. 7. A transmission electron microscopy image of a cluster of gold particles (diameter 15 nm). The cluster is a fractal object; the fractal dimension can be determined by a

In some colloidal systems the structure of the aggregates are found to be fractal objects. The Hausdorff fractal dimension D is generally defined by the following relation:¹³

$$N(r) = (r / r_0)^D \quad (1)$$

where $N(r)$ is the number of particles within a sphere of radius r and r_0 is the radius of the particles. Therefore, by counting the number of particles in the micrograph, the fractal dimension D can be calculated easily.

APPENDIX

Copies of Publications Related to Transmission Electron Microscopy

(From June 1987--date of installation of the TEM--to July 1988, present time)

APPENDIX

Copies of Publications Related to Transmission Electron Microscopy

(From June 1987--date of installation of the TEM--to July 1988, present time)

APPENDICES

Appendix - I

"Microstructural Characterization of $\text{YBa}_2\text{Cu}_3\text{O}_{7-x}$ "

M. Sarikaya, B. L. Thiel, and I. A. Aksay, W. J. Weber, and W. J. Frydrych

J. Mater. Res. **2** (6) Nov/Dec,

Appendix - II
"Local Structural Variations in $\text{YBa}_2\text{Cu}_3\text{O}_{7-x}$ "
M. Sarikaya and E. A. Stern
Phys. Rev. B, 37 (16), June, 1988

Appendix - III

"Structure and Formation of Twins in the Orthorhombic $\text{YBa}_2\text{Cu}_3\text{O}_{7-x}$ "

M. Sarikaya, R. Kikuchi, and I. A. Aksay

Physica C, **152**, 161 (1988).

Appendix - IV

"Identification of Intergranular Cu_2O in Polycrystalline $\text{YBa}_2\text{Cu}_3\text{O}_{7-x}$ "

M. Sarikaya and B. L. Thiel

J. Am. Ceram. Soc. 71 (6), June, C305-C309 (1988)

Appendix - V

"Local Structural Variations and Formation of Twins in the Orthorhombic $\text{YBa}_2\text{Cu}_3\text{O}_{7-x}$ "

M. Sarikaya, E. A. Stern, R. Kikuchi, and I. A. Aksay

Proc. MRS. Conf. Symp. on High Temperature Superconductors, D. W. Capone II, W. H. Butler, B. Batlogg, and C. W. Chu (Eds.), Spring (1988)

Appendix - VI

"Synthesis and Characterization of $\text{YBa}_2\text{Cu}_3\text{O}_{7-x}$ Superconductors"

W. J. Weber, L. R. Pederson, J. M. Prince, K. C. Davis, G. J. Exarhos, G. D. Maupin, J. T. Prater, and W. S. Frydrych, Battelle Pacific Northwest Laboratory; I. A. Aksay, B. L. Thiel, and M. Sarikaya, University of Washington

Advanced Ceramic Materials</

Appendix - VII

"Synthesis and Colloidal Processing of Superconducting $\text{YBa}_2\text{Cu}_3\text{O}_{7-x}$ "

I. A. Aksay, C. Han, R. Kurosky, S. McElhane, S. Pak, T. K. Yin, T. Yogo, R. M. Laine,
and M. Sarikaya

in *Proceedings of the Society for the Advancement of Materials and Process Engineering*, Seattle, June 16-17 (1988).

Appendix - VIII

"Substructural Variations in $\text{YBa}_2\text{Cu}_3\text{O}_{7-x}$ "

M. Sarikaya, R. Kikuchi, E. A. Stern, and I. A. Aksay

in *Proceedings of Society for the Advancement of Materials and Process Engineering*, Seattle,
June 16-17 (1988).

Appendix - IX

"Spinel Phase Formation During the 980°C Exothermic Reaction in the Kaolinite-to-Mullite
Reaction Series"

B. Sonuparlak, M. Sarikaya, and I. A. Aksay

J. Am. Ceram. Soc. **70** [11] 837-42 (1987)

Appendix - X

"In-Situ Preparation of Silica Within Hydrogels"

B. Tarasevich, I. A. Aksay, and M. Sarikaya

in *Atomic and Molecular Processing of Electronic and Ceramic Materials: Preparation, Characterization, and Properties*, Proceedings of the MRS Conference held August 30-September 2, 1987, University of Washington, Seattle, Washington, USA. Edited by I. A. Aksay, G. L. McVay, T. G. Stoebe, and J. F. Wager, (Materials Research Society, Pittsburgh, 1987) pp. 11

Appendix - XI

"Characterization of Interfaces in Ceramic-Metal Composites by High Resolution Transmission Electron Microscopy"

M. Sarikaya, D. L. Milius, and I. A. Aksay

in *Atomic and Molecular Processing of Electronic and Ceramic Materials: Preparation, Characterization, and Properties*, Proceedings of the MRS Conference held August 30-September 2, 1987, University of Washington, Seattle, Washington, USA. Edited by I. A. Aksay, G. L. McVay, T. G. Stoebe, and

Appendix - XII

"Characterization of Advanced Materials by High Resolution Transmission Electron Microscopy"

M. Sarikaya

in *Atomic and Molecular Processing of Electronic and Ceramic Materials: Preparation, Characterization, and Properties*, Proceedings of the MRS Conference held August 30-September 2, 1987, University of Washington, Seattle, Washington, USA. Edited by I. A. Aksay, G. L. McVay, T. G. Stoebe, and J. F. Wager, (Materials Research Society, Pittsburgh, 1987) pp. 211-226.

Appendix - XIII

"Structural Control with Ultrafine Particles"

J. Liu, M. Sarikaya, and I. A. Aksay

in *Proceedings of the 46th Annual Meeting of the Electron Microscopy Society of America*,
edited by G. W. Bailey (San Francisco Press, San Francisco, 1988), pp. 716-717.

Appendix - XIV

"Geometry and Formation of Twins in $\text{YBa}_2\text{Cu}_3\text{O}_{7-x}$ "

M. Sarikaya, R. Kikuchi, and I. A. Aksay

in *Proceedings of the 46th Annual Meeting of the Electron Microscopy Society of America*,
edited by G. W. Bailey (San Francisco Press, San Francisco, 1988), pp. 852-853.

Appendix - XV

"TEM Sample Preparation of Superconducting Oxides"

M. Sarikaya, B. L. Thiel, and J. P. Bradley

in *Proceedings of the 46th Annual Meeting of the Electron Microscopy Society of America*,
edited by G. W. Bailey (San Francisco Press, San Francisco, 1988), pp. 858-859.

Appendix - XVI

"Characterization of Intergranular Cuprous Oxide in Polycrystalline $\text{YBa}_2\text{Cu}_3\text{O}_{7-x}$ "

B. L. Thiel, C. Han, R. Kurosky, L. C. Hutter, I. A. Aksay, and M. Sarikaya
in *Proceedings of the 46th Annual Meeting of the Electron Microscopy Society of America*,
edited by G. W. Bailey (San Francisco Press, San Francisco, 1988), pp. 880-881.

